

# PATENT ABSTRACTS OF JAPAN

(11)Publication number : 64-009897  
(43)Date of publication of application : 13.01.1989

(51)Int.Cl. C30B 29/40  
C30B 25/14  
// H01L 21/205

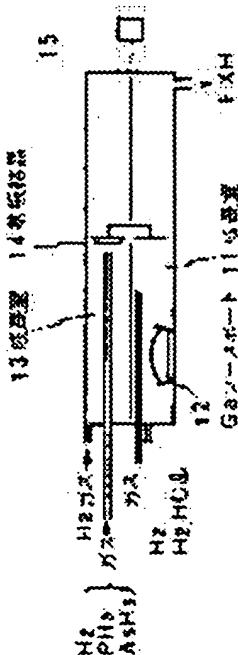
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## (54) METHOD FOR GROWING III-V COMPOUND SEMICONDUCTOR CRYSTAL ON SI SUBSTRATE

### (57)Abstract:

**PURPOSE:** To grow the titled superconductor crystal, having good crystallinity and capable of selective growth on a substrate, by alternately feeding a gas species containing a group III constituent element and a gas species containing a group V constituent element onto a silicon substrate having a formed mask pattern.

**CONSTITUTION:** A source boat 12 of a group III constituent element is placed on the upstream side of a growth chamber 11 in the lower stage and a carrier gas and HCl gas are fed from the upstream side thereof to adsorb the formed chloride of the group III constituent element on a silicon substrate 14 having a formed mask pattern. The substrate 14 is then moved to a growth chamber 13 in the upper stage and a gas species containing a group V constituent element is fed and adsorbed on the substrate 14. The above-mentioned operations are alternately repeated to carry out atomic layer epitaxial growth of a III-V compound semiconductor crystal on the substrate 14.



### LEGAL STATUS

[Date of request for examination]

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]